

FORM PTO-1449

**INFORMATION DISCLOSURE**

**STATEMENT BY APPLICANT**

(use as many sheets as necessary)

**Attorney Docket Number** 42637/GDL/N288

Application Number	To be assigned
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
Filing Date	December 17, 2001
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Applicant(s)	Jayant Neogi
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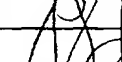

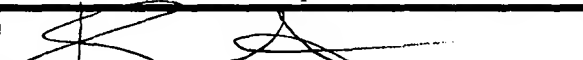
Group Art Unit	To be determined
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Examiner Name	To be determined
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## FOREIGN PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	PUBLICATION DATE	COUNTRY OR PATENT OFFICE	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
	WO 99/34197	07/1999	WIPO				
	2033096A	05/1980	GB	G03B	41/00		

## OTHER DOCUMENTS

EXAMINER INITIALS	Include name of the author (in CAPITAL LETTERS), title of the article, title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.		
	BRAUNSTEIN, et al., Depth profile of antimony implanted into diamond, Journal of Applied Physics, Vol. 50, No. 9, September 1979, Pgs. 5731 - 5735.		
	ENDENFELD et al., Force probe characterization using silicon three-dimensional structures formed by focused ion beam lithography, Journal of Vacuum Science and Technology B, Vol. 12, No. 6, 1994, Pgs. 3571-3575.		
	KOMURO, Ion Beam Exposure Apparatus Using Liquid Metal Source, 1982, Pgs. 155-159, Elsevier Squoia; Netherlands		
	International Search Report for PCT/US00/16761 Dated October 2, 2000		
EXAMINER SIGNATURE		DATE CONSIDERED	09/13/05
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.			

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